



SE MF-1000

MF-1000 Calibration Free!

Most ellipsometers require calibration process in each measurement to find the azimuths of all optical elements. This is a lengthy and complicated process.

However, SE MF-1000 is calibration free. This makes fast and accurate measurement.

MF-1000 Alignment Free!

MF-1000 is configured with a compact body using a built-in structure concept.

All optical, mechanical and electrical components are arranged precisely into one compact body.

MF-1000 operates easily without effort for alignment.

Feature

Easy Operation

- No set up
- No effort for alignment (sample faces down)
- Calibration free (patented)
- No keys to control
- Maintenance free (except lamp)

Fast Measurement

- 5 sec for full spectra

Specification

- | | |
|---------------------------|--|
| • Wavelength | 350 ~ 840 nm or 1.5 ~ 3.5 eV |
| • Measurement items | Film thickness, n, k |
| • Accuracy ₁ | 1048.85 Å ± 0.29 Å for 1049 Å SiO ₂ on c-Si |
| • Thickness range | 1 Å ~ 3 μm (depends on sample) |
| • Throughput ₂ | 5 ~ 10 sec per point (depends on sample) |
| • Angle of Incidence | 70 ± 0.5 (Fixed angle of incidence) |
| • Sample size | 8 mm x 8 mm ~ 200 mm x 200 mm |
| • Foot print | 280 mm (W) x 200 mm (D) x 60 mm (H) |
| • Weight | 6 kg (typical) |

Foot note

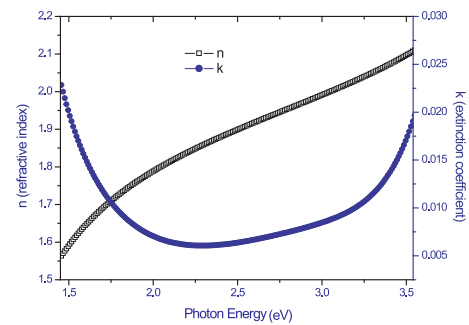
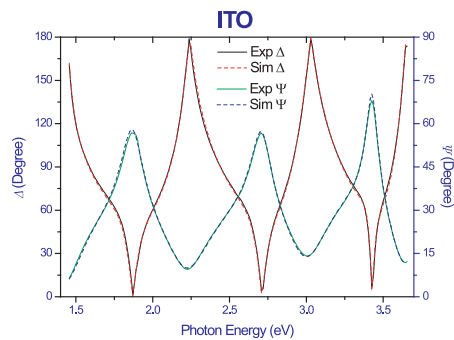
1. Thickness measurement on specular sample Accuracy is the precision, where a static sample is repeatedly measured at the same spot and is described as three times of standard deviation.

2. Throughput is the time of 1 point static sample measurement.

SE MF-1000



Application for TCO



Spectroscopic ellipsometry measurement of ITO coating on silicon wafer.
The real(n) and imaginary(k) part of the complex refractive index of ITO film.

Application for Dielectrics

